

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10532459			
<b>Filing Date:</b>	02-Nov-2005			
<b>Title of Invention:</b>	METHOD OF POLYCRYSTALLIZATION, METHOD OF MANUFACTURING POLYSILICON THIN FILM TRANSISTOR, AND LASER IRRADIATION DEVICE THEREFOR			
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<b>Filer:</b>	Hugh Hakushu Matsubayashi/sheila badon			
<b>Attorney Docket Number:</b>	AB-1432 US			
Filed as Large Entity				
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
Utility Appt issue fee	1501	1	1440	1440
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Total in USD (\$)				1740